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(54) **COMBINED PUMPING SYSTEM
COMPRISING A GETTER PUMP AND AN ION
PUMP**

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See application file for complete search history.

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(57) **ABSTRACT**

A combined pumping system comprising a getter pump and an ion pump is described. The getter pump and the ion pump are mounted in series on a same flange and are respectively arranged on opposite sides thereof so that both getter and ion pumps conductance are maximized towards gas flux sources in a vacuum chamber in order to improve the vacuum level of the system.

11 Claims, 4 Drawing Sheets

